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PCT

PATENT
8038-1062



IN THE U.S. PATENT AND TRADEMARK OFFICE

In re application of

Takayuki SHIMAMUNE et al.

Conf. 2298

Application No. 10/527,801
(PCT/JP/03/11656)

PCT/DO/EO

Filed March 14, 2005

PROCESS FOR PRODUCING HIGH-PURITY
SILICON AND APPARATUS

SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

November 14, 2005

Sir:

In compliance with Rules 1.97 and 1.98, and in fulfillment of the duty of disclosure under Rule 1.56, the accompanying document, a copy of which is attached to this statement, is made of record on the enclosed Form PTO-1449.

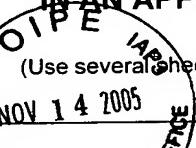
A concise explanation of the relevance of this item is that this reference (JP 2003-342016) was cited in the corresponding International application but erroneously identified in the search report as 2003-242016.

Respectfully submitted,

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RJP/fb

INFORMATION DISCLOSURE CITATION IN AN APPLICATION <div style="text-align: right; margin-top: -10px;">  (Use several sheets if necessary) </div>			Attorney Docket No.: 8038-1062		Application No.: 10/527,801	
			Applicant: Takayuki SHIMAMUNE et al.			
			Filing Date: March 14, 2005		Group Art Unit:	
U.S. PATENT DOCUMENTS						
Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing date (if appropriate)
FOREIGN PATENT DOCUMENTS						
Examiner Initial	Document Number	Date	Country	Class	Subclass	Translation Yes No
	2003-342016 (with English abstract)	12/3/03	Japan			X
OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)						
EXAMINER:			DATE CONSIDERED			

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant.

* Abstract provided for the Examiner's convenience